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PATENT

Atty Docket No.: 200308991-1
App. Ser. No.: 10/826,288

IN THE CLAIMS:

Please find below a listing of all of the pending claims. The statuses of the claims are set forth in parentheses.

1. (Currently Amended) A method of making a microelectromechanical system device comprising:

releasing a micromover component;

coating the micromover component with a first ~~self-aligned~~ film after releasing the micromover component, the first film being configured to store data; and

affixing contact probes to the device after coating the micromover component, the contact probes being configured to read the stored data.

2. (Currently Amended) The method of claim 1, wherein the step of coating comprises selectively depositing a coating composition [[only]] on a surface of the micromover component without going over an edge of the surface by using a difference in surface tension over the edge.

3. (Original) The method of claim 1, wherein the film comprises at least one of a polymer, PMMA and an epoxy photoresist.

4. (Original) The method of claim 3, wherein the polymer is thermoplastic.

5. (Currently Amended) The method of claim 3, wherein the first film is configured to store data as indentations on the first filmpolymer is thermoset.

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6. (Original) The method of claim 1, wherein coating the micromover component comprises adjusting a coating parameter to control the film thickness.

7. (Original) The method of claim 6, wherein adjusting a coating parameter comprises selecting a solid to solvent ratio.

8. (Currently Amended) The method of claim 1 [[6]], wherein at least some of the contact probes is configured to be pressed into the first film to create indentations on the first film after softening of the first film by applying heat to the first film ~~adjusting a coating parameter comprises selecting an amount of film material to deposit.~~

9. (Original) The method of claim 1, further comprising plasma treating a surface of the micromover component prior to coating.

10. (Original) The method of claim 9, further comprising applying an adhesion promoter to the micromover component after plasma treating.

11. (Currently Amended) The method of claim 1, further comprising coating the micromover component with a second ~~self-aligned~~ film.

12. (Currently Amended) The method of claim 11, wherein the second ~~self-aligned~~ film comprises a different material from the first ~~self-aligned~~ film.

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13. (Currently Amended) The method of claim 12, wherein one of the ~~self-aligned~~ films comprises a thermoplastic polymer and the other comprises a thermoset polymer.

14. (Currently Amended) The method of claim 12, wherein the first ~~self-aligned~~ film and the second ~~self-aligned~~ film have different hardness.

15. (Currently Amended) The method of claim 12, wherein the first ~~self-aligned~~ film and the second self-aligned film have different glass transition temperatures.

16. (Currently Amended) The method of claim 1, further comprising bonding a wafer having at least one contact probe or AFM tip opposite the ~~self-aligned~~ film, the at least one contact probe and the AFM tip each being one of the contact probes affixed to the device.

17. (Original) The method of claim 16, further comprising fabricating a contact atomic resolution storage device.

18. (Currently Amended) The method of claim 1, wherein the first ~~self-aligned~~ film is adapted for data storage, anti-wear, anti-reflective, desiccant or an anti-stiction.

19-42. (Canceled).

43. (New) A method of making a microelectromechanical system device comprising:

releasing a micromover component;

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coating the micromover component with a film after releasing the micromover component; and

affixing contact probes to the device after coating the micromover component, the contact probes being configured to be pressed into the film to create indentations on the film after softening of the film by applying heat to the film, the indentations on the film being configured to store data.

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